L Number	Hits	Search Text	DB	Time stamp
1	3047820	(micro adj1 mirror) manufactur$5	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/02 12:28
2	17770	mirror near7 substrate	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/02 12:18
3	86428	form$5 near7 hinge$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/02 12:19
4	266	((micro adj1 mirror) manufactur$5) and (mirror near7 substrate) and (form$5 near7 hinge$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/02 12:20
5	152628	resist$5 near2 layer	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/02 12:20
6	55982	dry near5 etching	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/02 12:21
7	38	(((micro adj1 mirror) manufactur$5) and (mirror near7 substrate) and (form$5 near7 hinge$3)) and (dry near5 etching)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/02 12:21
8	15	(resist$5 near2 layer) and ((((micro adj1 mirror) manufactur$5) and (mirror near7 substrate) and (form$5 near7 hinge$3)) and (dry near5 etching))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/02 12:21
9	1		USPAT	2004/08/02 12:27
10	502	(micro adj1 mirror) and hinge$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/02 12:28
11	266	((micro adj1 mirror) manufactur$5) and (mirror near7 substrate) and ((micro adj1 mirror) and hinge$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/02 12:29
12	3	(resist$5 near2 layer) and (dry near5 etching) and (((micro adj1 mirror) manufactur$5) and (mirror near7 substrate) and ((micro adj1 mirror) and hinge$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/02 12:30
13	22	(dry near5 etching) and (((micro adj1 mirror) manufactur$5) and (mirror near7 substrate) and ((micro adj1 mirror) and hinge$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/08/02 12:30

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